

## Development of Ultrananocrystalline Diamond (UNCD) Coatings

Presented by

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Materials, Sensors & Automation, and Glass Project Review June 21-24, 2004
Arlington, Virginia



A U.S. Department of Energy Office of Science Laboratory Operated by The University of Chicago





## **Project Summary**

#### Goal:

- Use UNCD to achieve significant energy savings in IOF industries
  - First application SiC multipurpose mechanical pump seals

### Challenge:

- Develop technology to take UNCD from laboratory to market application
  - Need to mass produce UNCD coated parts

### Benefits:

- Improved wear resistance and corrosion resistance of UNCD coated parts
- 20% energy savings of 236 trillion Btu by 2020 in pump applications primarily due to reduced friction losses

### • FY05 Activities:

- Commission and optimize 11-inch IPLAS system (up from 6-inch system)
  - Demonstrate UNCD coating of multiple seals simultaneously
- Demonstrate benefits of UNCD coatings on gas seals
- Verify tribological benefits of UNCD coated seals
  - Perform long-term pump tests





## Project Participants – Laboratory-led project

### Argonne National Laboratory

- Energy Systems:
  - Jeff Elam, John Hryn (Project POC), Joe Libera
- Energy Technology:
  - Ali Erdemir, Andriy Kovalchenko
- Materials Science:
  - Orlando Auciello, John Carlisle, Dieter Gruen, Mike Pellin, Alex Zinovev

### Industry Partners:

- Advanced Diamond Technologies, Inc. (ADT)
  - Neil Kane (Industry POC)
- John Crane, Inc.
- IPLAS Innovative Plasma Systems
- Morgan Advanced Ceramics
- Northwestern University
- University of Illinois at Chicago





## Barriers - Pathways - Critical Metrics

- 1) Uniform nucleation and growth of UNCD
  - 1) smooth films
  - 2) good adhesion

Understand plasma
deposition and surface
seeding requirements,
UNCD characterization
and testing

Develop seeding protocol to produce uniform UNCD films (COMPLETED)

Scale – up UNCD deposition process

Commission 11-inch plasma system

Multiple seals coated with UNCD simultaneously

Limited seal testing facilities

Use industrial facilities and expand lab capabilities

Perform successful pilot test (data indicate energy savings)

4) Commercialization of UNCD technology

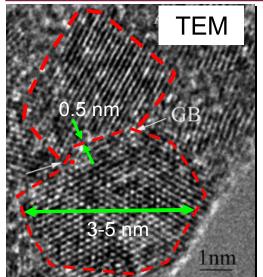
Launch company (ADT)

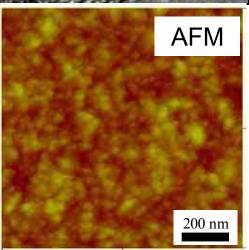
Sign toll-processing agreement





## Ultrananocrystalline Diamond (UNCD) Properties





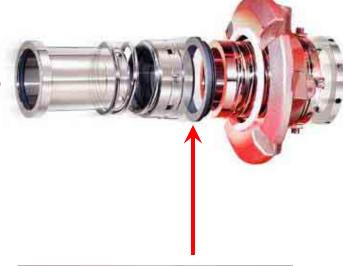
- Hardness 97 GPa
- Elastic Modulus 970 GPa
- Fracture Strength 5 GPa
- Grain Size 2 5 nm
- RMS Roughness 0.5 1 µ-inch
- Friction Coefficient 0.03





## **UNCD** for Multipurpose Mechanical Pump Seals







**UNCD Coating** 







# Technical Barrier #1: Uniform nucleation and growth of UNCD

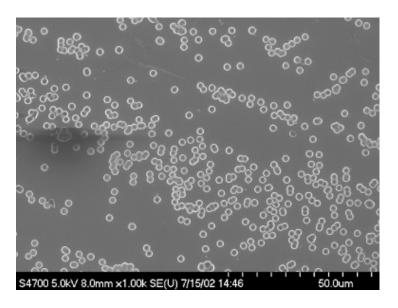
- Seeding to achieve smooth UNCD films
- Seeding to achieve excellent adhesion of UNCD to SiC Seal

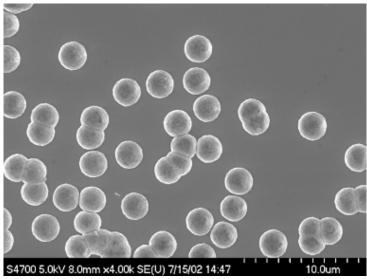




## UNCD - Example of Poor Seeding

### Sample: Unseeded CVD SiC





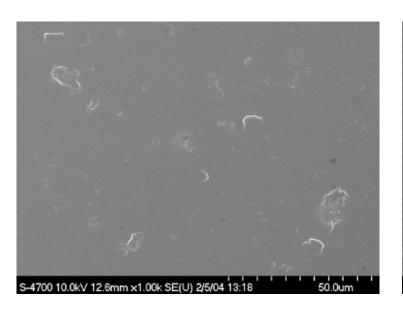
Low nucleation density – discontinuous coating

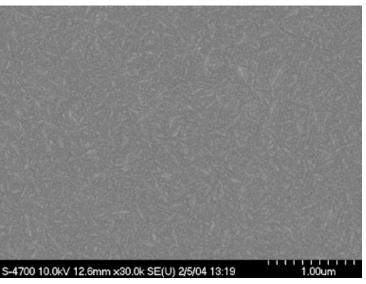




## **UNCD – Example of Excellent Seeding**

Sample: Mechanically Seeded α-SiC





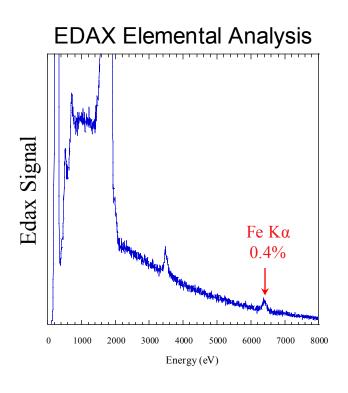
High nucleation density - dense, continuous, smooth film

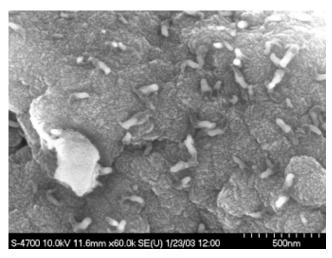


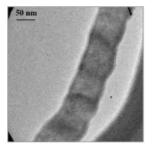


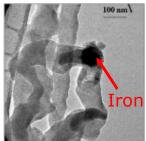
### Simultaneous UNCD and Carbon Nanofiber (CNF) Growth

### SEM and TEM Following UNCD Treatment









SEM, TEM shows CNF with iron particle catalyst

Trace Fe Contamination Catalyzes CNF Growth

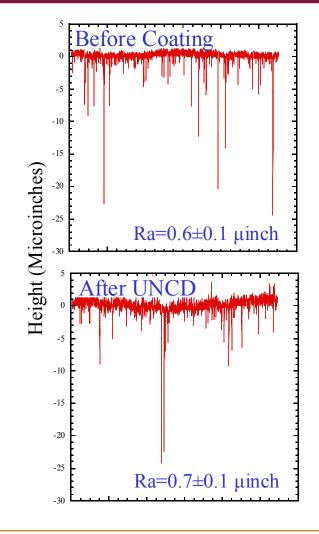




## UNCD Coating of Smooth 2" OD α-SiC Seals







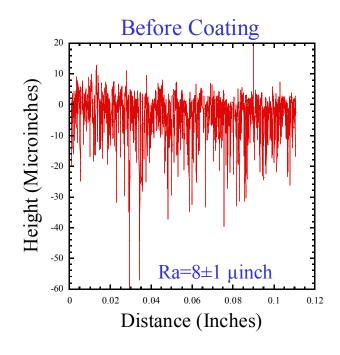




## UNCD Coating of Rough 1" OD α-SiC Seals



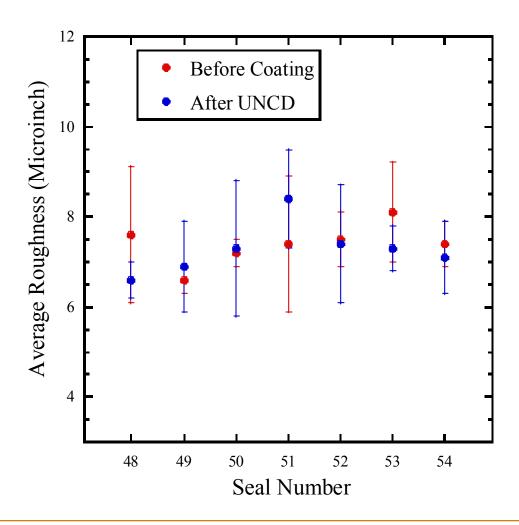








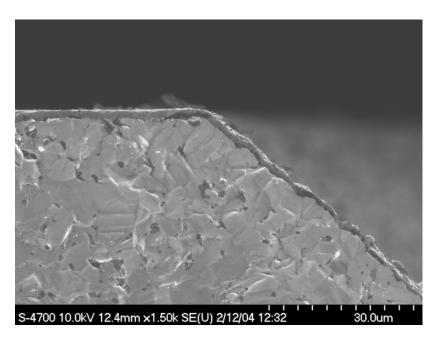
## Roughness Measurements of Rough 1" OD Seals Following UNCD Coating







## Adhesion Measurements Using Fracture Analysis



S-4700 10.0kV 12.5mm ×15.0k SE(U) 2/12/04 12:36 3.00um

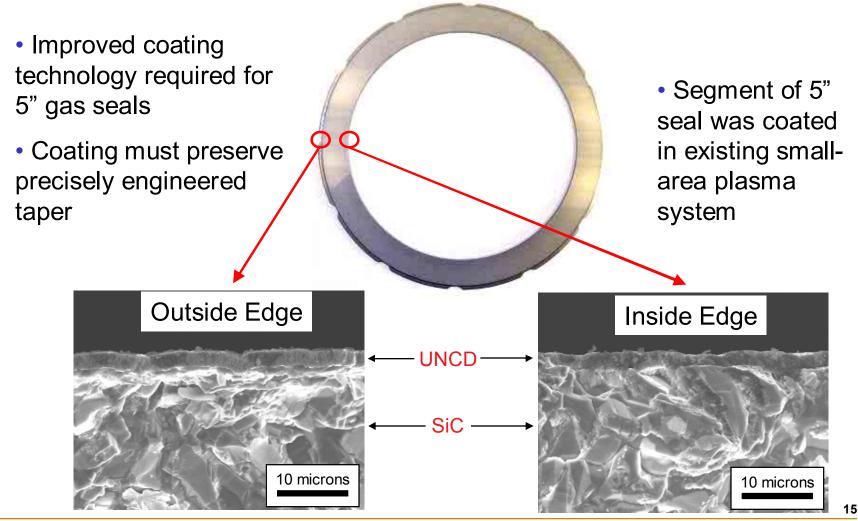
Conformal UNCD coating over Seal face and beveled edge

Fracture of UNCD-SiC interface observed after diamond saw cutting (1). However, fracture also observed along SiC grains (2) and UNCD film (3)





## UNCD Coating of 5" Gas Seals







# Technical Barrier #2: Scale – up UNCD deposition process

## IPLAS 11" Microwave Plasma CVD System



- First unit of its kind in the world
- Will enable batch-coating of multiple 2" seals
- Will enable coating of intact 5" seals





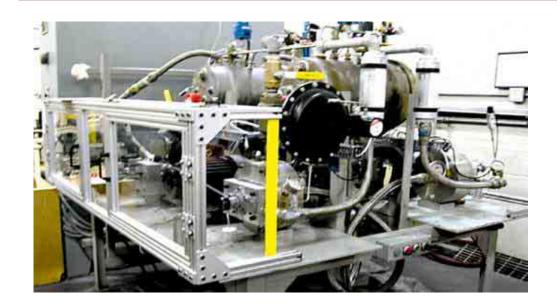
# Technical Barrier #3: Limited seal testing facilities

- Building Test Pump Loop at Argonne for Measuring Seal Friction and Wear
- Installed Surface Profiler at Argonne
- Friction and Wear Analysis at John Crane Testing Facilities





### Hot Water Test of UNCD-Coated Seals at John Crane



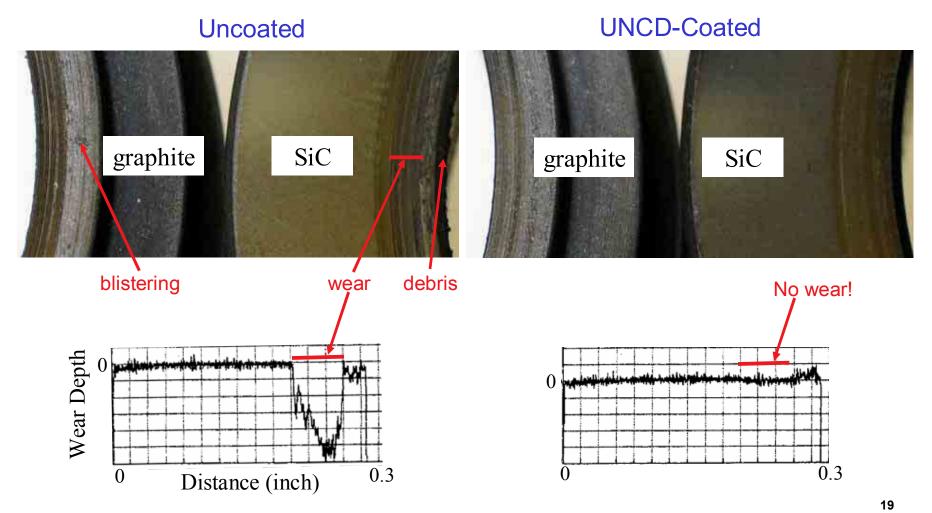
- 2" OD Seal
- 100 Hours

- Very aggressive test of materials properties
- Mimics harsh conditions in chemical process pump
- 100 hour test simulates 2 years of extreme use





### Hot Water Test of UNCD-Coated Seals

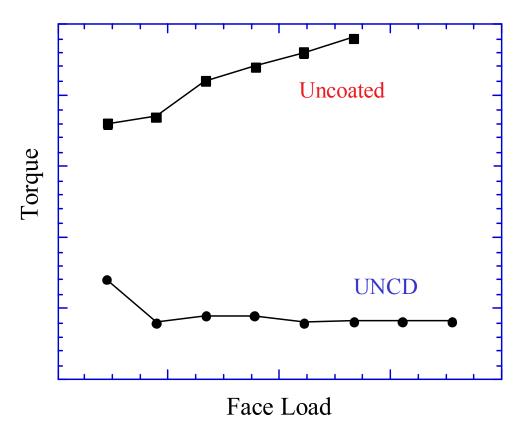






### Friction Measurements of UNCD Coated 2" SiC Seal

### Low Initial Roughness



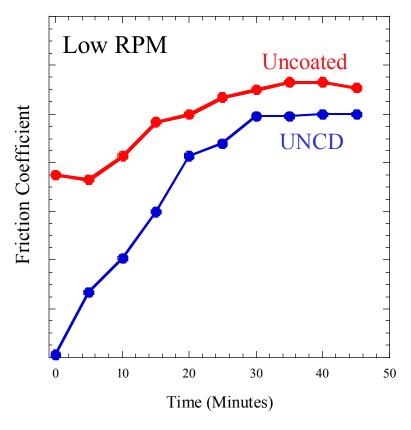
Significantly Reduced Friction for Smooth Seal Surface





### Friction Measurements of UNCD Coated 1" SiC Seal

### High Initial Roughness



Marginally Reduced Friction for Rough Seal Surface







# Technical Barrier #4: Commercialization of UNCD technology



### Advanced Diamond Technologies

- Argonne-initiated start-up company
  - Exclusive license in UNCD application
- Company officially launched in 2003
- Business plan established
- Toll processor for seal manufacturers
  - Agreements in principle reached with partners





## Future Work Leading to Commercialization

### FY05

- Understand effect of initial substrate roughness on UNCD friction
- Commission and optimize 11-inch IPLAS system (up from 6-inch system)
  - Demonstrate UNCD coating of multiple 2" seals simultaneously
- Demonstrate benefits of UNCD coatings on gas seals
- Verify tribological benefits of UNCD coated seals
  - Perform long-term pump tests

### FY06-07

- Pilot tests (field tests): 2" seals, 5" seals
- Automation of UNCD deposition process

### FY07

- Commercialization (sign toll-processing agreements)
- Final report



